

WHAT IS CLAIMED IS:

1. A vacuum arc evaporation source, comprising:  
a plurality of cathodes including different kinds of  
materials from one another and being insulated electrically from  
5 one another,

wherein said plurality of cathodes are evaporated by vacuum  
arc discharge to thereby generate plasma having cathode  
materials.

2. The vacuum arc evaporation source according to Claim  
1, wherein said plurality of cathodes are disposed coaxially  
with one another through an insulating material.

3. The vacuum arc evaporation source according to Claim  
1, wherein said plurality of cathodes includes a cathode having  
a material containing carbon and a cathode having a material  
containing metal of a group 4A, 5A or 6A in the periodic table.

4. The vacuum arc evaporation source according to Claim  
2, wherein each of said cathodes has a circular shape.

5. A film formation apparatus for forming a laminate  
film including a plurality of heterogeneous films on a surface  
of a substrate, the apparatus comprising:

a vacuum arc evaporation source having a plurality of

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cathodes including different kinds of materials from one another  
and being insulated electrically from one another, wherein said  
plurality of cathodes are evaporated by vacuum arc discharge  
to thereby generate plasma having cathode materials on a surface  
of the cathode;

an arc power supply for supplying arc discharge power to  
said plurality of cathodes of said vacuum arc evaporation  
source; and

a switch for alternatively changing over the arc discharge  
power of said arc power supply toward said plurality of cathodes  
of said vacuum arc evaporation source.

6. A film formation apparatus for forming a laminate  
film including a plurality of heterogeneous films on a surface  
of a substrate, the apparatus comprising:

a vacuum arc evaporation source having a plurality of  
cathodes including different kinds of materials from one another  
and being insulated electrically from one another, wherein said  
plurality of cathodes are evaporated by vacuum arc discharge  
to thereby generate plasma having cathode materials on a surface  
of the cathode; and

a magnetic filter for generating a magnetic field to curve  
plasma generated by said vacuum arc evaporation source so as  
to removes coarse particles from the plasma and introduce the  
plasma, the coarse particles of which is removed, into vicinity

of the substrate.

7. The film formation apparatus according to claim 6,  
wherein said magnetic filter comprises:

- 5 a curved transport duct;  
a magnetic coil for generating the magnetic field curved  
along said transport duct; and  
a DC power supply for exciting said magnetic coil.

10 8. The film formation apparatus according to claim 6,  
further comprising:

an arc power supply for supplying arc discharge power to  
the plurality of cathodes of said vacuum arc evaporation source;  
and

15 a switch for alternatively changing over the arc discharge  
power of said arc power supply toward said plurality of cathodes  
of said vacuum arc evaporation source.

9. The film formation apparatus according to claim 8;  
20 wherein said magnetic filter comprises

- a curved transport duct;  
a magnetic coil for forming the magnetic field curved along  
said transport duct; and  
a DC power supply for exciting said magnetic coil.

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10. The film formation apparatus according to claim 5;  
further comprising:

5) a magnet disposed adjacent to the other surface of the  
cathode opposite to the surface on which the plasma is generated,  
for controlling a motion of an arc point of the vacuum arc  
discharge.

11. The film formation apparatus according to claim 6;  
further comprising:

10 a magnet disposed adjacent to the other surface of the  
cathode opposite to the surface on which the plasma is generated,  
for controlling a motion of an arc point of the vacuum arc  
discharge.

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